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Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 127104			APPLICATION NO. 10/569,207	
INFORMATION DISCLOSURE STATEMENT								
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			FILING Februar	DATE y 23, 2006		GROUP 2872		
	r	U.	.S. PATEN	T DOCUM	MENTS			
Examiner Initials	Cite No.	Document Number	Date		Name			
	1	6,417,974	07/09/20	02 Schuster				
	2	2001/0043320 A1	11/22/20	01	Kato et al.			
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	3	EP 1 152 263 A1	11/07/20	01	EPO			
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	6 M. SWITKES et al., Immersion Liquids for Lithography in the Deep Ultraviolet, Optical Microlithography XVI, 2003, 690-6 Vol. 5040 (2003)							
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